

CERTIFICATE OF TRANSMISSION BY FACSIMILE (37 CFR 1.8)Applicant(s): **Hidemitsu Aoki, et al.**

Docket No.

12688ASerial No.
10/075,566Filing Date
February 13, 2002Examiner
Saeed ChaudhryGroup Art Unit
1746Invention: **METHOD FOR CLEANING SEMICONDUCTOR WAFER AFTER
CHEMICAL MECHANICAL POLISHING ON COPPER WIRING**I hereby certify that this TRANSMITTAL (w/ Certified Copy of Japanese Patent Appln. No. 10-138365)*(Identify type of correspondence)*is being facsimile transmitted to the United States Patent and Trademark Office (Fax. No. (571) 273-1296on February 5, 2004*(Date)*Richard J. Danyko*(Typed or Printed Name of Person Signing Certificate)**(Signature)*

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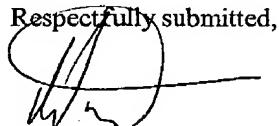
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**Applicant(s):** Hidemitsu Aoki, et al.**Examiner:** Saeed Chaudhry**Serial No.:** 10/075,566**Art Unit:** 1746**Filed:** February 13, 2002**Docket:** 12688A**For:** METHOD FOR CLEANING
SEMICONDUCTOR WAFER AFTER
CHEMICAL MECHANICAL POLISHING
ON COPPER WIRING**Dated:** February 5, 2004

Commissioner for Patents
Mail Stop Non-Fee Amendment
Arlington, VA 22313

TRANSMITTAL

Sir:

Pursuant to the undersigned's conversation with Examiner Chaudhry, enclosed is a facsimile of the certified copy of the priority document.

Respectfully submitted,


Richard J. Danyko
Registration No. 33,672

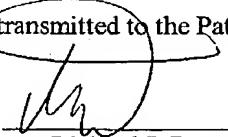
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